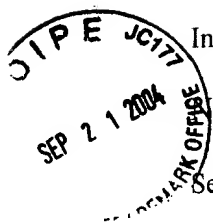


IN THE UNITED STATES PATENT AND TRADEMARK OFFICE



In re application of

: **Confirmation No. 1632**

Norio KIMURA et al.

: Docket No. 2001-0660A

Serial No. 09/864,208

: Group Art Unit 1763

Filed May 25, 2001

: Examiner Sylvia MacArthur

SUBSTRATE POLISHING APPARATUS AND  
SUBSTRATE POLISHING METHOD

**Mail Stop: RCE**

**PETITION FOR EXTENSION OF TIME**

Commissioner for Patents  
P.O. Box 1450  
Alexandria, VA 22313-1450

Sir:

Petition hereby is made for a one month extension of time to respond to the communication of May 21, 2004.

The fee of \$110.00 is

☒ (X) submitted herewith.

☐ ( ) to be charged to Deposit Account No. 23-0975. A duplicate copy of this Petition is enclosed.

☐ ( ) Small entity status of this application is established by a Small Entity Status Assertion which

☐ ( ) is enclosed.

☐ ( ) has been previously submitted.

THE COMMISSIONER IS AUTHORIZED  
TO WAIVE ANY DEFICIENCY IN THE  
FILES FOR THIS PAPER TO DEPOSIT  
ACCOUNT NO. 23-0975

09/22/2004 HVUONG1 00000093 09864208

02 FC:1251

110.00 OP

NEP/krq  
Washington, D.C. 20006-1021  
Telephone (202) 721-8200  
Facsimile (202) 721-8250  
September 21, 2004

Respectfully submitted,

Norio KIMURA et al.

By

Nils E. Pedersen  
Registration No.33,145  
Attorney for Applicants